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**José Sasián
Richard N. Youngworth**
Editors

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Introduction

"Unfortunately, alignment is often considered only when one confronts the hardware. This is often too late, since system constraints have been determined."

Richard N. Shagam (Cochair of Optical Alignment), SPIE Volume 251, 1980

This year marked the seventh time this annual conference has taken place in beautiful San Diego, California, USA at SPIE Optics + Photonics 2013. This year's Optical System Alignment, Tolerancing and Verification VII conference was again very successful. The conference consisted of a day of high quality presentations, the poster session, and subsequent proceedings articles. Specifically, this year the conference had four strong sessions on tolerancing and instrument alignment, alignment and optomechanics, alignment testing and electro-optics, and verification of optical systems. We sincerely thank our invited speakers, contributed speakers, poster paper presenters, and the superb community for making the sessions and conference such a success. It is very clear that the topics covered by this conference continue to be of great interest to the optics and photonics community.

The history of SPIE conferences on Optical Alignment dates back to 1980. The most recent embodiment started in 2007 by José Sasián and Mitch Ruda. The listing of years and conference chairs for optical alignment (to 1993), optical system alignment and tolerancing (2007 to 2008), and, finally, addition of the topic of verification (2009-present) are:

- 1980 Richard N. Shagam and William C. Sweatt
- 1984 Mitch Ruda
- 1986 Mitch Ruda
- 1993 Mitch Ruda
- 2007 J. Sasián and M. Ruda
- 2008 J. Sasián and R. N. Youngworth
- 2009 J. Sasián and R. N. Youngworth
- 2010 J. Sasián and R. N. Youngworth
- 2011 J. Sasián and R. N. Youngworth
- 2012 J. Sasián and R. N. Youngworth
- 2013 J. Sasián and R. N. Youngworth

We must of course thank our excellent program committee for continuing to promote this conference. Furthermore, we are once again quite grateful to the greater community for sharing work and participating, as interaction in this area is very beneficial in advancing our field. Finally, we thank the volunteers and SPIE staff for providing us the opportunity to cover the subjects of optical system

alignment, tolerancing, and verification in a dedicated conference and proceedings.

This conference will continue in 2014. We encourage everyone interested in optical system alignment, tolerancing, and verification to look for the call for papers and to submit your work in early 2014. Please feel free to contact us or anyone on our program committee if you have any questions.

Finally, and most importantly in our hearts, is to mark the passing of one of the true and pure greats in the optics community, Dr. Mitch Ruda. Mitch was absolutely essential in the formation of this conference and served with us for a number of years to help highlight the importance of optical alignment. Many of us have known Mitch, worked with him, learned from him, and admired his very strong body of work. He will be greatly missed by the entire optics community.

José Sasián
Richard N. Youngworth